

RESPONSE TO OFFICE ACTION

Serial No. 10/805,890

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**IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE**

PATENT APPLICATION

Applicant: Nallan, et al.

Case: 7017C1/ETCH/METAL-NVM/JB

Serial No.: 10/805,890

Filed: March 22, 2004

Examiner: Tran, Binh X

Group Art Unit: 1765

Confirmation No.: 1896

Title: **METHOD OF PLASMA ETCHING OF HIGH-K DIELECTRIC MATERIALS WITH
HIGH SELECTIVITY TO UNDERLYING LAYERS**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450.

SIR:

RESPONSE TO FINAL OFFICE ACTION DATED SEPTEMBER 20, 2006

In response to the Final Office Action dated September 20, 2006, having a statutory period for response set to expire on December 20, 2006, please enter this response and reconsider the claims pending in the application for the reasons discussed below. The Terminal Disclaimer fee under 37 C.F.R. §1.20(d) has been paid on-line at the Patent Office Electronic Business Center. Although the Applicants believe that no other fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.